

## Special Issue

# Corrosion and Etching at Micro/Nanoscale

### Message from the Guest Editors

I am very glad to invite you to contribute to this Special Issue of *Micromachines*. Corrosion and etching at micro (nano) scale is an important topic in several fields, from the fabrication of sensors and membranes to investigations of the properties of micro- and nano-composites. The study of this phenomena is essential to acquire knowledge on the physical and mechanical properties of synthesized materials and their resistance to corrosion. This Special Issue is devoted to the review and discussion of all theoretical and practical aspects of these processes. Both experimental and theoretically based contributions related to fabrication via etching processes and the characterization of corrosion resistance in microdevices and composites are welcome.

---

### Guest Editors

Dr. Giorgio Luciano

Institute for Chemical Technologies, National Research Council of Italy, Rome, Italy

Dr. Małgorzata Norek

Institute of Materials Science & Engineering, Faculty of Advanced Technology & Chemistry, Military University of Technology, Warsaw, Poland

---

### Deadline for manuscript submissions

closed (31 December 2021)



## Micromachines

---

an Open Access Journal  
by MDPI

---

Impact Factor 3.0  
CiteScore 6.0  
Indexed in PubMed



[mdpi.com/si/49559](https://mdpi.com/si/49559)

*Micromachines*  
Editorial Office  
MDPI, Grosspeteranlage 5  
4052 Basel, Switzerland  
Tel: +41 61 683 77 34  
[micromachines@mdpi.com](mailto:micromachines@mdpi.com)

[mdpi.com/journal/  
micromachines](https://mdpi.com/journal/micromachines)





# Micromachines

---

an Open Access Journal  
by MDPI

---

Impact Factor 3.0  
CiteScore 6.0  
Indexed in PubMed



[mdpi.com/journal/  
micromachines](https://mdpi.com/journal/micromachines)



## About the Journal

### Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

---

### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

---

### Author Benefits

#### High Visibility:

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

#### Journal Rank:

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

#### Rapid Publication:

manuscripts are peer-reviewed and a first decision is provided to authors approximately 17.2 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the first half of 2025).